

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

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Title of Invention

METHODS OF THINNING A SILICON WAFER USING HF AND
OZONE

Application Number : 10/631376
Confirmation Number: 2135
First Named Applicant: Eric Bergman
Attorney Docket Number: 54008.8033.US00
Art Unit: 1746
Examiner: Zeinab El-Arini
Search string: (6162734 or 6806205).pn



US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6162734	1995-10-12	Bergman et al.			
	2	6806205	2000-12-29	Jang et al.	B2		

Signature

Examiner Name	Date